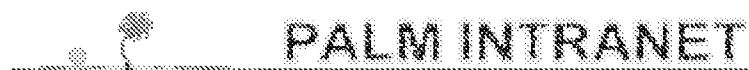


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Inventor Name Search Result

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Last Name = SCHEDEL

First Name = THORSTEN

Application#	Patent#	Status	Date Filed	Title	Inventor Name
09946940	Not Issued	161	09/04/2001	Method of adjusting a lithographic tool	SCHEDEL, THORSTEN
10112271	6593254	150	03/28/2002	METHOD FOR CLAMPING A SEMICONDUCTOR DEVICE IN A MANUFACTURING PROCESS	SCHEDEL, THORSTEN
10134106	6684124	150	04/29/2002	METHOD FOR CONTROLLING A PROCESSING DEVICE FOR A SEQUENTIAL PROCESSING OF SEMICONDUCTOR WAFERS	SCHEDEL, THORSTEN
10175591	6780552	150	06/19/2002	METHOD FOR CONTROLLING THE QUALITY OF A LITHOGRAPHIC STRUCTURING STEP	SCHEDEL, THORSTEN
10190097	6806008	150	07/03/2002	METHOD FOR ADJUSTING A TEMPERATURE IN A RESIST PROCESS	SCHEDEL, THORSTEN
10435449	6887722	150	05/09/2003	METHOD FOR EXPOSING A SEMICONDUCTOR WAFER	SCHEDEL, THORSTEN
10635583	6979522	150	08/06/2003	METHOD FOR EXPOSING AT LEAST ONE OR AT LEAST TWO SEMICONDUCTOR WAFERS	SCHEDEL, THORSTEN
10686848	6861331	150	10/16/2003	METHOD FOR ALIGNING AND EXPOSING A SEMICONDUCTOR WAFER	SCHEDEL, THORSTEN
10694594	6892108	150	10/27/2003	METHOD FOR ADJUSTING PROCESSING PARAMETERS OF AT LEAST ONE PLATE-SHAPED OBJECT IN A PROCESSING TOOL	SCHEDEL, THORSTEN
10713690	6908775	150	11/14/2003	METHOD FOR PERFORMING	SCHEDEL,

				AN ALIGNMENT MEASUREMENT OF TWO PATTERNS IN DIFFERENT LAYERS ON A SEMICONDUCTOR WAFER	THORSTEN
10715073	Not Issued	71	11/17/2003	Configuration and method for detecting defects on a substrate in a processing tool	SCHEDEL, THORSTEN
10717413	7248365	150	11/19/2003	METHOD FOR ADJUSTING A SUBSTRATE IN AN APPLIANCE FOR CARRYING OUT EXPOSURE	SCHEDEL, THORSTEN
10950165	7186484	150	09/24/2004	METHOD FOR DETERMINING THE RELATIVE POSITIONAL ACCURACY OF TWO STRUCTURE ELEMENTS ON A WAFER	SCHEDEL, THORSTEN
10965693	Not Issued	41	10/14/2004	Method for producing a mask adapted to an exposure apparatus	SCHEDEL, THORSTEN
11127304	7304716	150	05/12/2005	METHOD FOR PURGING AN OPTICAL LENS	SCHEDEL, THORSTEN
11170191	Not Issued	30	06/29/2005	Method for the preferred processing of workpieces of highest priority	SCHEDEL, THORSTEN
11967165	Not Issued	25	12/29/2007	Method for Enhancing the Adhesion of a Passivation Layer on a Semiconductor Device	SCHEDEL, THORSTEN

Inventor Search Completed: No Records to Display.

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